

Title (en)

INTERFEROMETRIC DETERMINATION OF A LAYER THICKNESS

Title (de)

INTERFEROMETRISCHE SCHICHTDICKENBESTIMMUNG

Title (fr)

DETERMINATION INTERFEROMETRIQUE D'EPAISSEUR DE COUCHE

Publication

EP 1931941 A1 20080618 (DE)

Application

EP 06764297 A 20060802

Priority

- EP 2006064954 W 20060802
- DE 102005045512 A 20050922
- DE 102006016132 A 20060406

Abstract (en)

[origin: WO2007033851A1] The invention relates to an interferometric measuring apparatus for measuring thicknesses of partially transparent layers on substrates, especially carbon-based wear-resistant layers. Said measuring apparatus comprises a scanning device which automatically scans the layers in the vertical direction (Z) thereof and by means of which an interference plane (IE) can be moved relative to the layer structure, and an interferometer part (IT) that is provided with a white light interferometer (WLI) and/or a wavelength scanning interferometer (WLSI). The invention further relates to a corresponding evaluation method.

IPC 8 full level

G01B 11/06 (2006.01); **G01B 9/02** (2006.01)

CPC (source: EP US)

G01B 11/0675 (2013.01 - EP US)

Citation (search report)

See references of WO 2007033851A1

Citation (examination)

US 2005088663 A1 20050428 - DE GROOT PETER J [US], et al

Designated contracting state (EPC)

DE FR GB

DOCDB simple family (publication)

WO 2007033851 A1 20070329; EP 1931941 A1 20080618; JP 2009509149 A 20090305; US 2009296099 A1 20091203

DOCDB simple family (application)

EP 2006064954 W 20060802; EP 06764297 A 20060802; JP 2008531633 A 20060802; US 99240206 A 20060802